



THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Daniel Alvarez, Jr. and Jeffrey J. Spiegelman

Application No.: 10/692,018 Group: 1724

Filed: October 23, 2003 Examiner: Unknown

Confirmation No.: 8519

For: METHOD FOR PURIFICATION OF LENS GASES USED  
IN PHOTOLITHOGRAPHY

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PRELIMINARY AMENDMENT

Mail Stop Missing Parts  
Commissioner for Patents  
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Sir:

Please amend the application as follows: